

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**Form PTO-1449 (Modified)
(Use several sheets if necessary)**COMPLETE IF KNOWN**

Application Number	09/651,779
Confirmation Number	2448
Filing Date	August 30, 2000
First Named Inventor	Scott E. Moore
Group Art Unit	3723
Examiner Name	Dung V. Nguyen
Attorney Docket No.	108298515US

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U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.	U.S. Patent or Application		Name of Patentee or Inventor of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		NUMBER	Kind Code (if known)			
	AA	U.S. Application No. 09/651,808 (Atty. Docket No. 4373US)		Chopra et al.	Filed 08/30/2000	
	AB	U.S. Application No. 09/653,392 (Atty. Docket No. MTI-31044)		Chopra et al.	Filed 08/31/2000	
	AC	U.S. Application No. 09/887,767 (Atty. Docket No. 10829.8515US2)		Lee et al.	Filed 06/21/2001	
	AD	U.S. Application No. 09/888,002 (Atty. Docket No. 10829.8515US3)		Lee et al.	Filed 06/21/2001	
	AE	U.S. Application No. 09/888,084 (Atty. Docket No. 10829.8515US1)		Lee et al.	Filed 06/21/2001	
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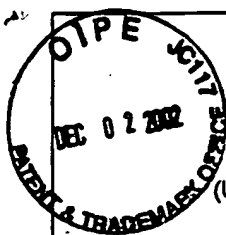
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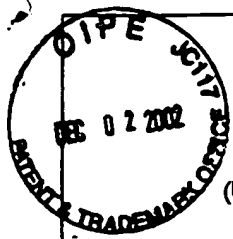
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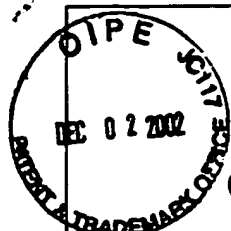
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		Office	NUMBER				
	CB	WO	00/26443	Talieh	05/11/2000		
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	CD	WO	00/32356	Talieh	06/08/2000		
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	CF	WO	00/59682	Talieh	10/12/2000		

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Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume issue number(s), publisher, city and/or country where published.	T

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	CI	HUANG, C.S. et al., "A Novel UV Baking Process to Improve DUV Photoresist Hardness", pp. 135-138.	
	CJ	McGraw-Hill, <i>Concise Encyclopedia of Science & Technology</i> , Sybil P. Parker, Editor-in-Chief, Fourth Edition, p. 367, McGraw-Hill, New York, New York, 1998.	
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